

FORM PTO-1449 (10-96 MODIFIED)
LIST OF PUBLICATIONS FOR APPLICANT'S
INFORMATION DISCLOSURE STATEMENT


Substitute for form 1449A/PTO INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(use as many sheets as necessary)</i>				<i>Complete if Known</i>	
				Application Number	Not Yet Assigned 10/806,680
				Filing Date	March 22, 2004
				First Named Inventor	Narain D. Arora
				Group Art Unit	Not Yet Assigned 2825
				Examiner Name	Not Yet Assigned LIN, SUN J.
Sheet	1	of	2	Attorney Docket Number 700693-4026	

U.S. PATENT DOCUMENTS						
Examiner Initials		Document No.	Date	Name of Patentee or Applicant	Class/SubClass	Filing Date (if appropriate)
JSA	AA	5,999,010	12/07/1999	Narain D. Arora, et. al.	324/765	12/08/1997
JSA	AB	6,291,254	09/18/2001	Shih-tsun Alexander Chou	438/18	02/04/1999
JSA	AC	6,312,963	11/06/2001	Shih-Tsun Alexander Chou	438/18	02/04/1999

FOREIGN DOCUMENTS							
Examiner Initials		Document No.	Publication Date	Country	Class/SubClass	Translation	
						Yes Abstract	No
						<input type="checkbox"/>	<input type="checkbox"/>
						<input type="checkbox"/>	<input type="checkbox"/>

OTHER DOCUMENTS		
Examiner Initials		Author, Title, Date, Pertinent Pages, Etc.
JSA	CA	N.D Arora, L. Song, S. Shah, K. Joshi, K. Thumaty, A. Fujimura, J.P. Schoelkopf, H. Brut, M. Smayling, T. Nagata; Cadence Design Systems, San Jose, CA 95135; STMicroelectronics, Crolles, France, 38926; Applied Materials, Santa Clara, CA 95054; Test Chip Characterization Of X Architecture Diagonal Lines For Soc Design; 5 pages.
JSA	CB	Narain D. Arora; Cadence Design Systems, Inc., San Jose, CA 95134, USA; Modeling And Characterization Of Copper Interconnects For Soc Design; 6 pages.
JSA	CC	Dae-Hyung Cho, Man-Ho Seung, Nam-Ho Kim, and Hun-Sup Park; Measurement And Characterization Of Multi-Layered Interconnect Capacitance For Deep Submicron Vlsi Technology; 4 pages; Proc. IEEE 1997 Int. Conference on Microelectronic Test Structures, Vol, 10, March 1997.
JSA	CD	James C. Chen, Dennis Sylvester, and Chenming Hu; An On-Chip, Interconnect Capacitance Characterization Method With Sub-Femto-Farad Resolution; 7 pages; Vol. 11, No. 2, May 1998.

OTHER DOCUMENTS		
Examiner Initials		Author, Title, Date, Pertinent Pages, Etc.
JA	CE	Narain D. Arora and Li Song; Atto-Farad Measurement And Modeling Of On-Chip Coupling Capacitance; 1 of 3 pages; IEEE Electron Device Letters, IEEE Transactions on Semiconductor Manufacturing, Vol. 25, No. 2, February 2004.

Examiner Signature		Date Considered	11-21-05
-----------------------	---	--------------------	----------

- * **EXAMINER:** Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.